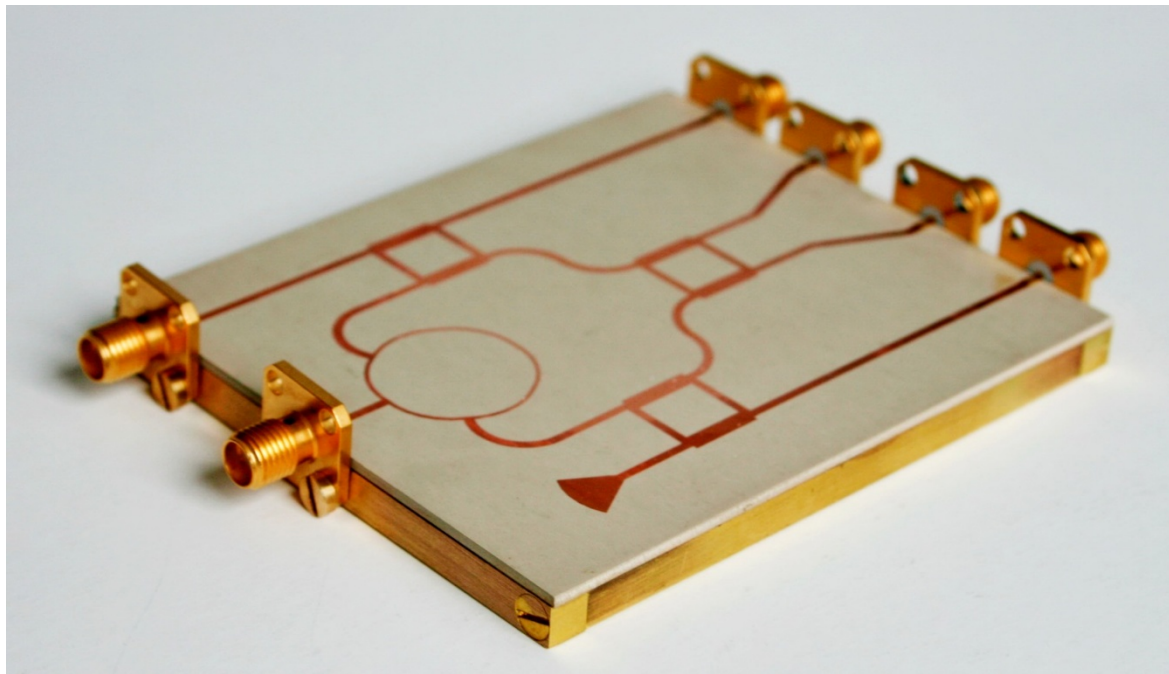


DEVELOPMENT OF A MODIFIED SIX-PORT DISCRIMINATOR FOR PRECISE BEAM POSITION MEASUREMENTS



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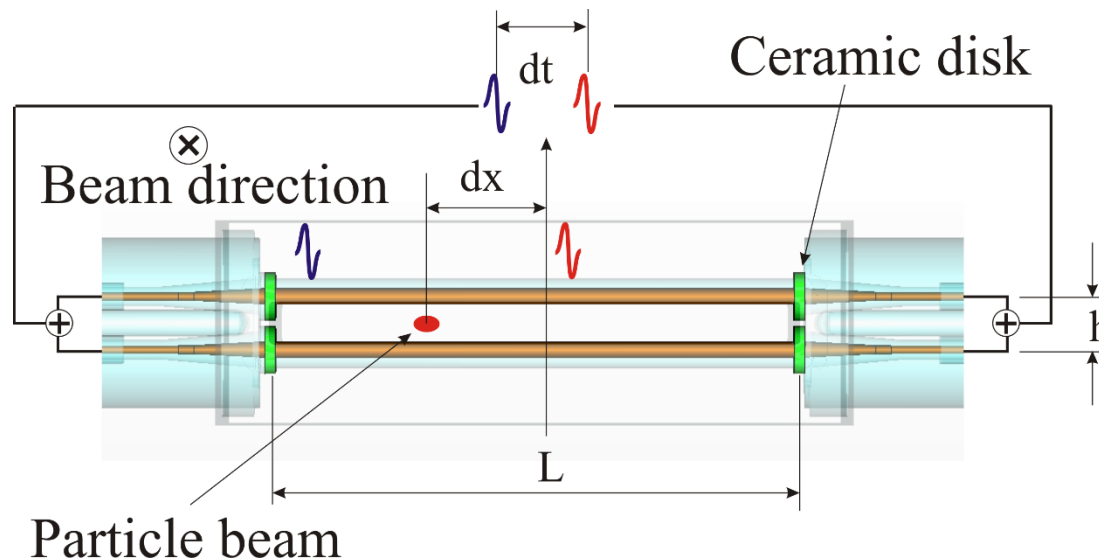
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- Motivation - Energy BPM for FLASH and XFEL
- Six-Port Reflectometer
- System Measurements
- Conclusion & Outlook

New Energy Beam Position Monitors for FLASH and European XFEL

- EBPM: Energy Beam Position Monitor in the dispersive section of a bunch compressor chicane for energy measurements
- Position measurement proportional to bunch energy $dx \sim \frac{dE}{E}$
- Current implementation at FLASH



New Energy Beam Position Monitors for FLASH and European XFEL

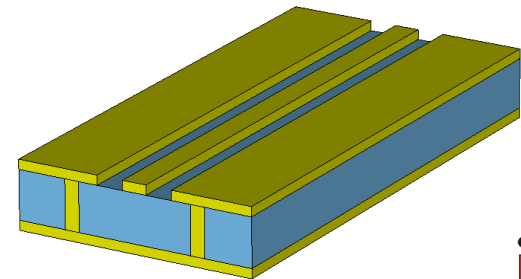
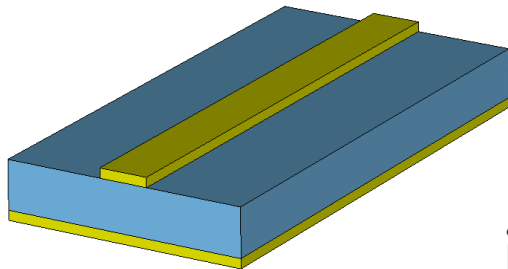
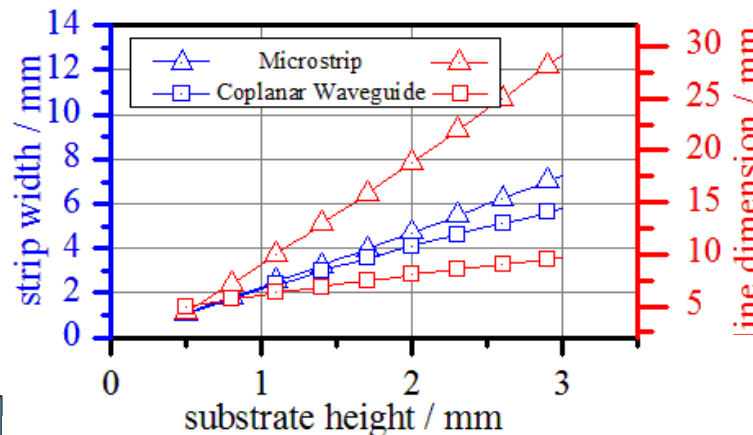
- Upgrade of EBPMs at FLASH and European XFEL necessary
- Design parameters for FLASH and the European XFEL

	FLASH	XFEL
L [mm]	183	400
H [mm]	8	40.5
Frequency [GHz]	1.3	3
Bunch charge [pC]	<200	20

- Improved, mechanical stable design of the pickup structures necessary

New Energy Beam Position Monitors for FLASH and European XFEL

Planar transmission line pickups



- Microstrip transmission line as a **Baseline** design¹ for FLASH and XFEL

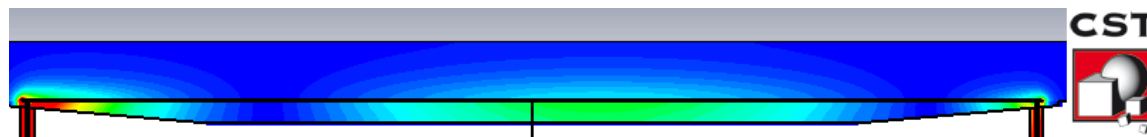
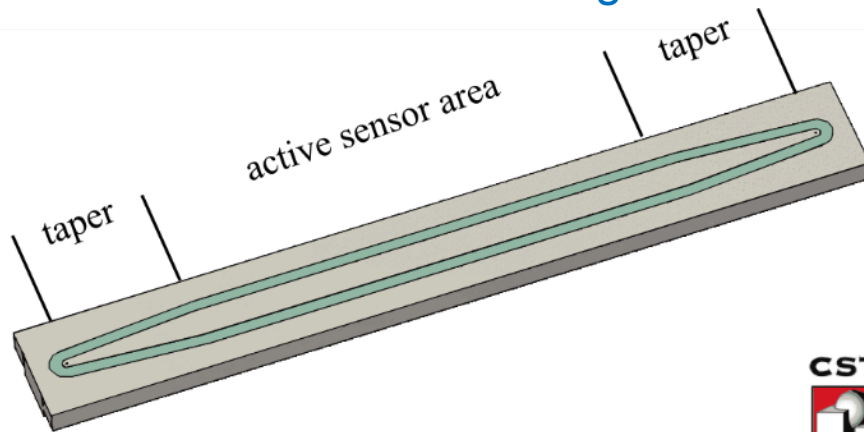
¹Angelovski et al. MOPA47, IBIC 2012, Tsukuba, Japan

² Penirschke et al. TUPC29, IBIC 2013, Oxford, UK

- Grounded coplanar waveguide transmission line as an **Improved** option² for FLASH and XFEL

New Energy Beam Position Monitors for FLASH and European XFEL

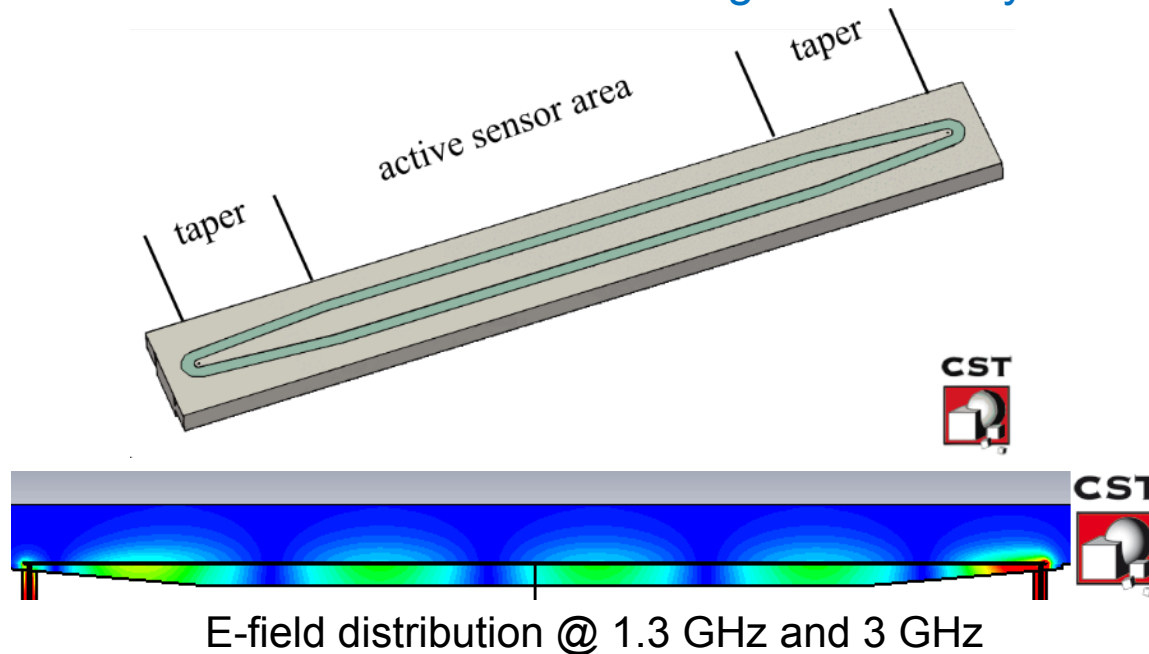
- Taper of substrate height improves the input reflection
- Complicated structure; fabrication with standard substrate hardly possible
 - ✓ Substrate made of melted glass in cavity



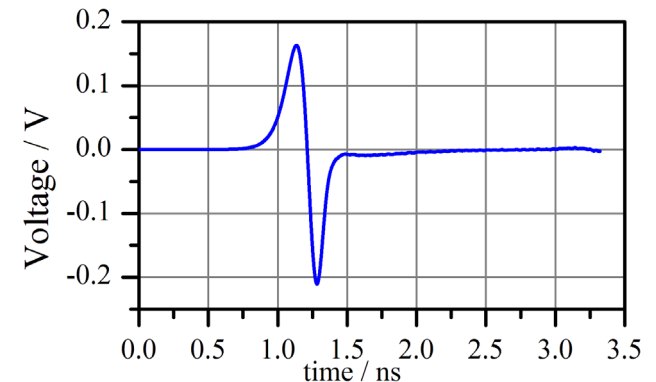
E-field distribution @ 1.3 GHz and 3 GHz

New Energy Beam Position Monitors for FLASH and European XFEL

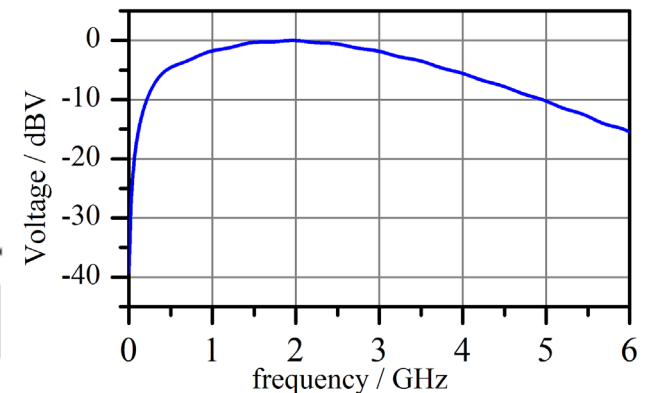
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Pickup voltage signal @ 20pC



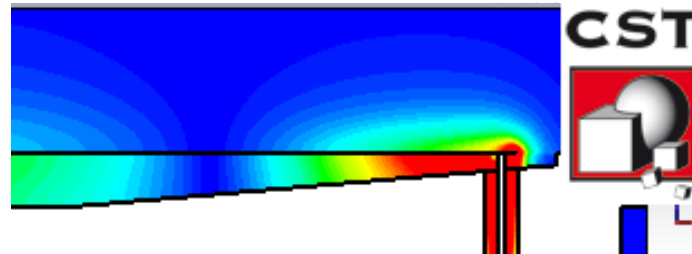
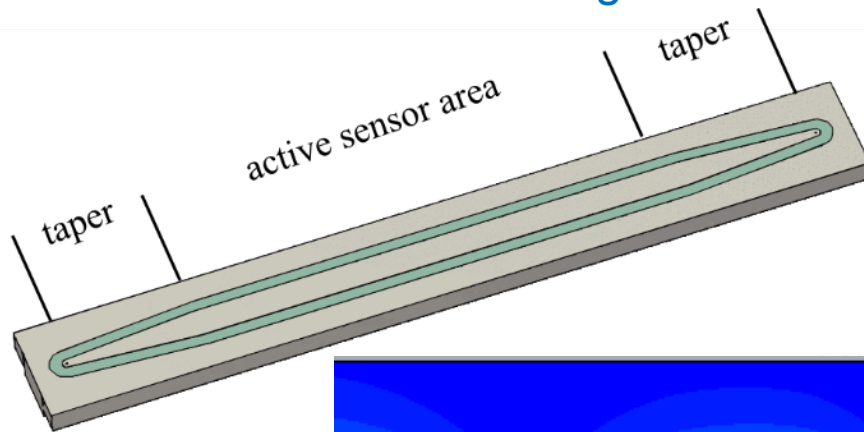
Time domain



Frequency domain

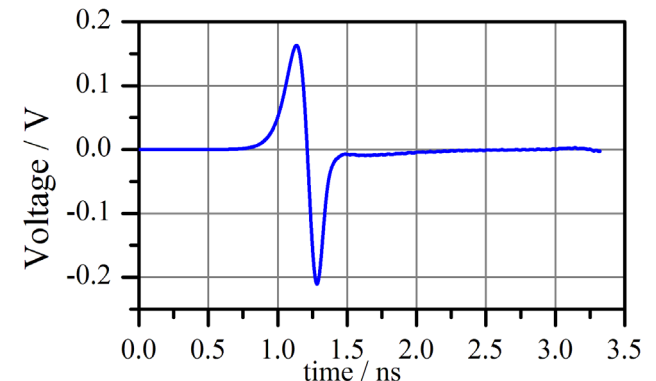
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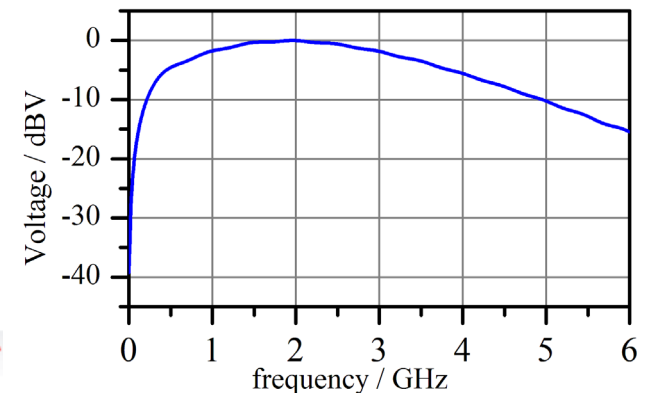


E-field distribution @ 1.3 GHz and 3 GHz

Pickup voltage signal @ 20pC



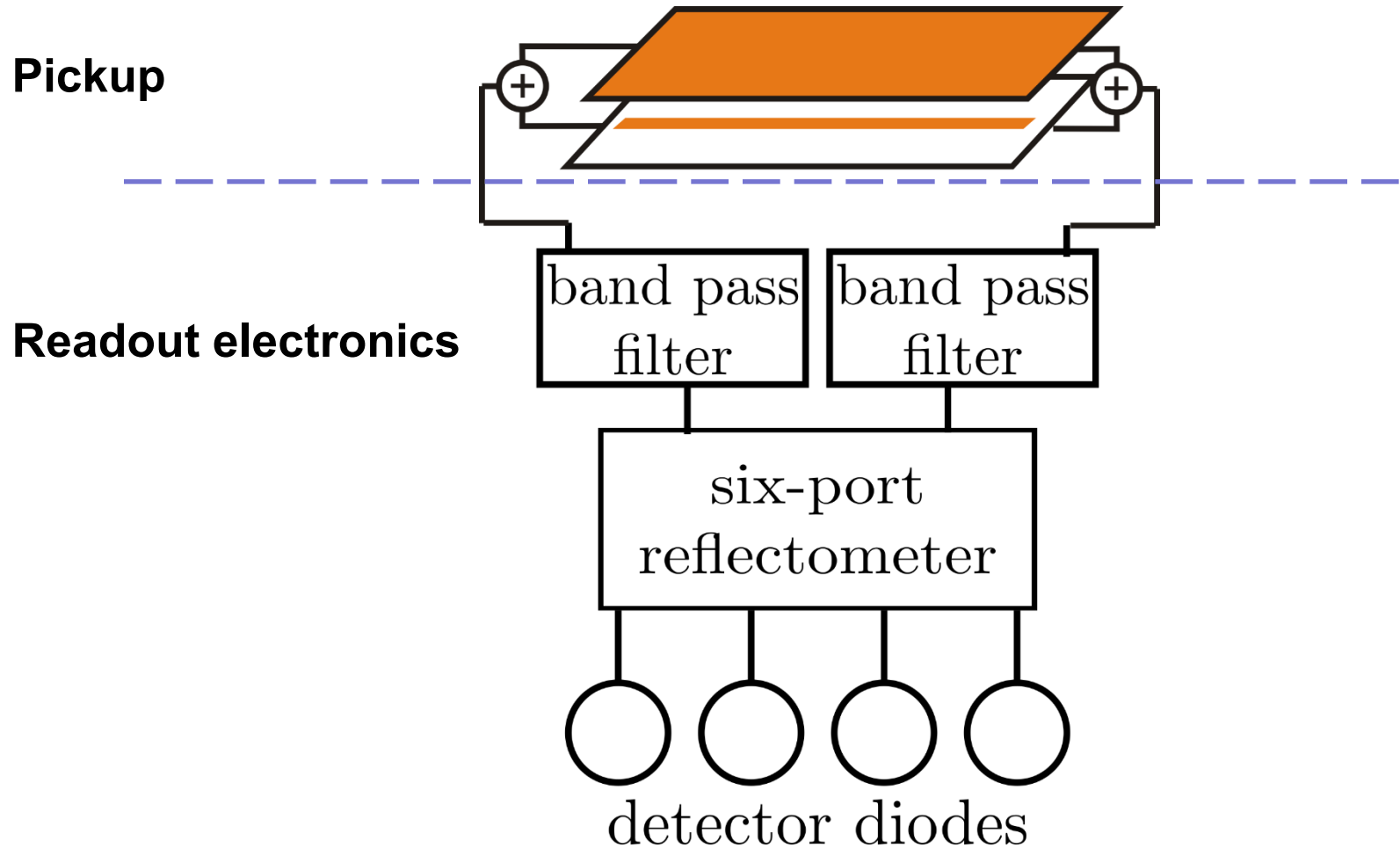
Time domain



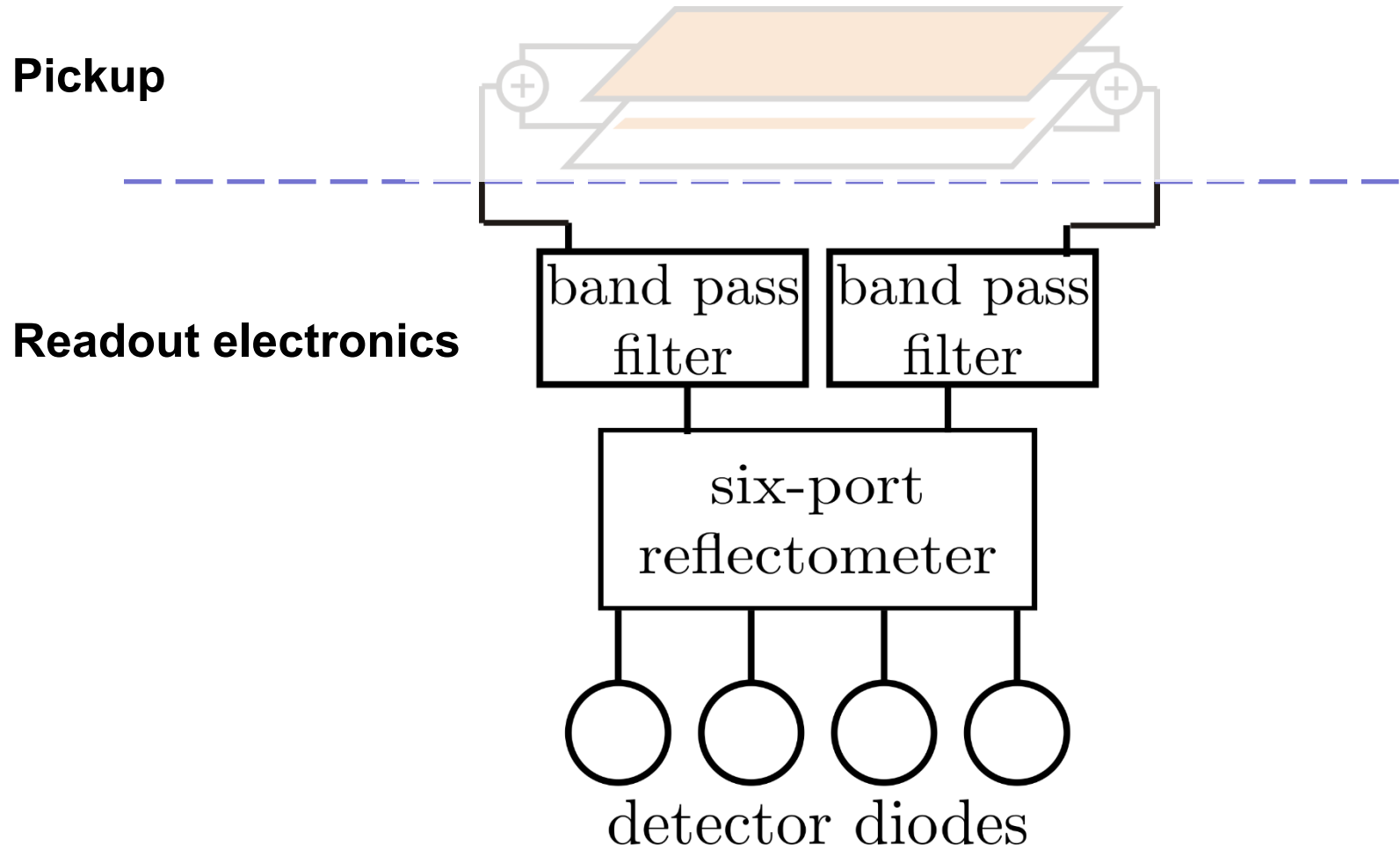
Frequency domain

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- Six-Port Reflectometer
- System Measurements
- Conclusion & Outlook

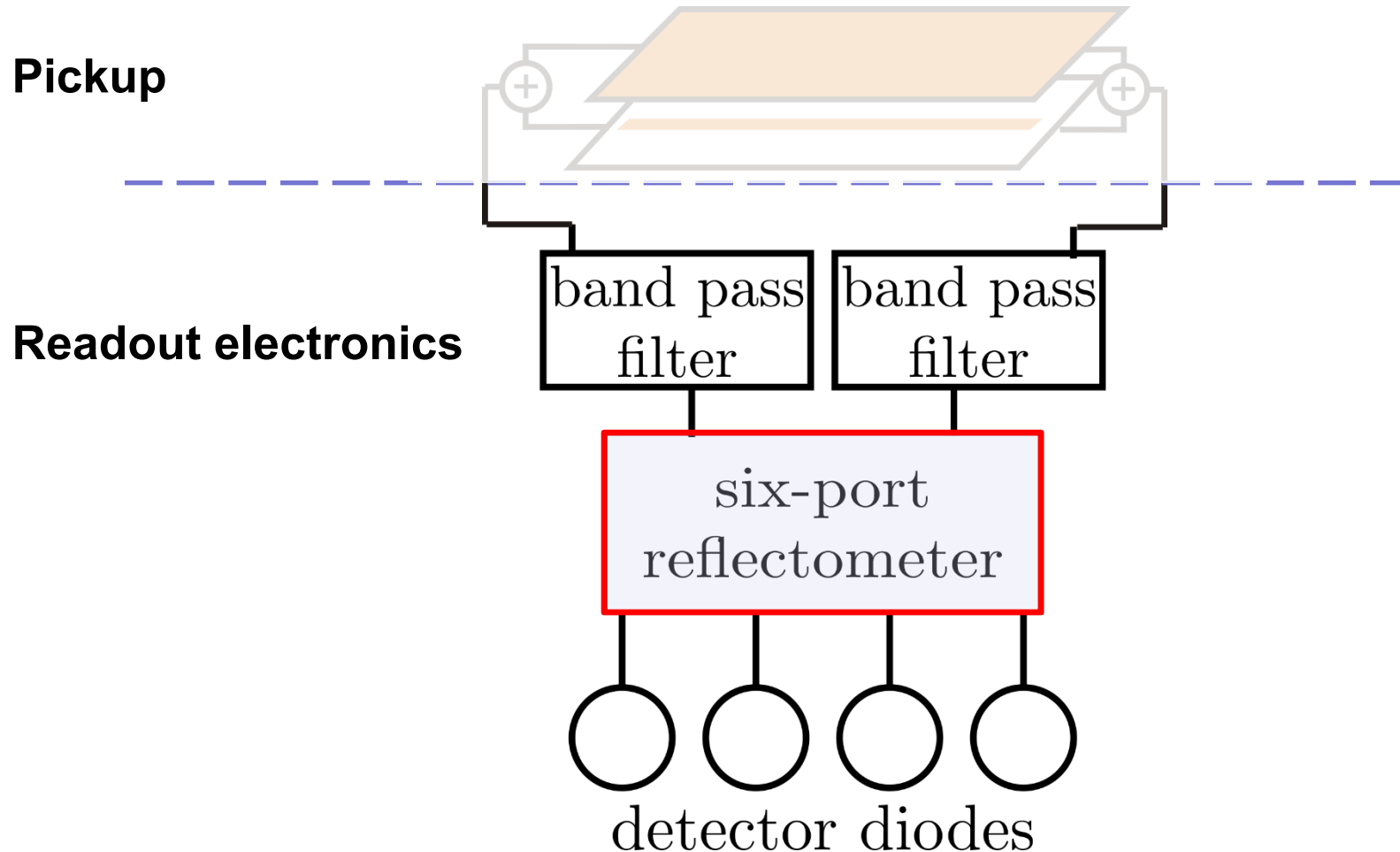
Six-Port Reflectometer for Phase Difference Measurements



Six-Port Reflectometer for Phase Difference Measurements

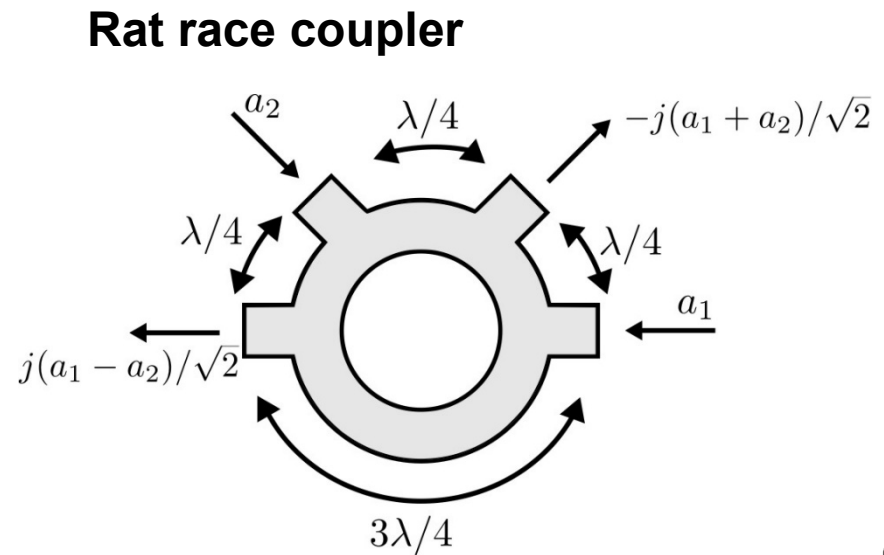
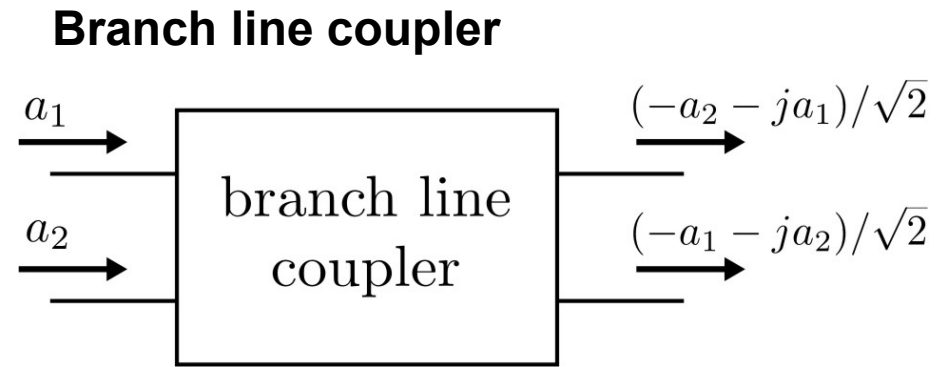
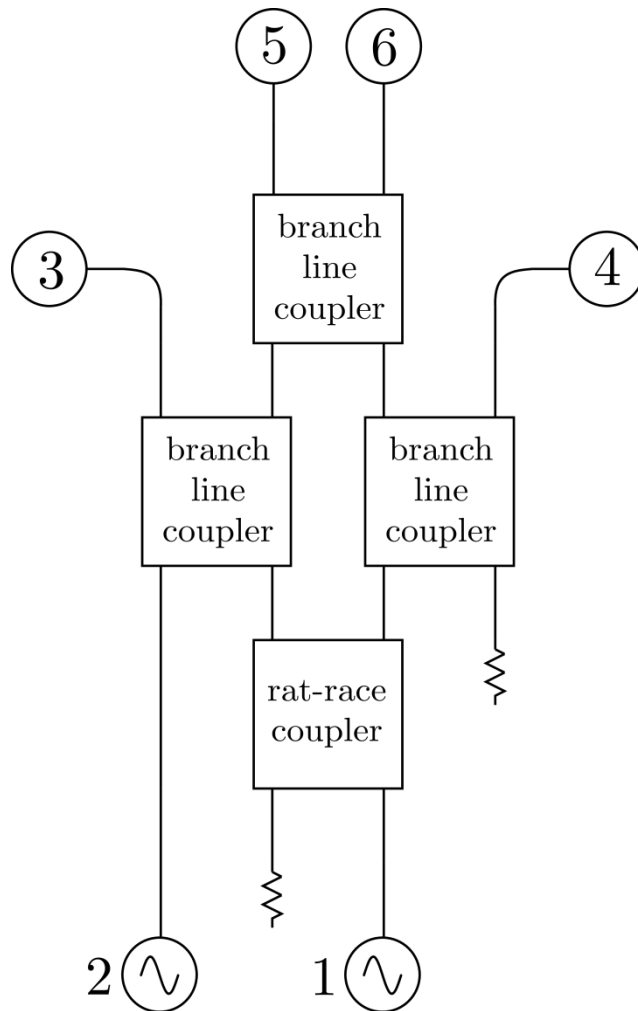


Six-Port Reflectometer for Phase Difference Measurements



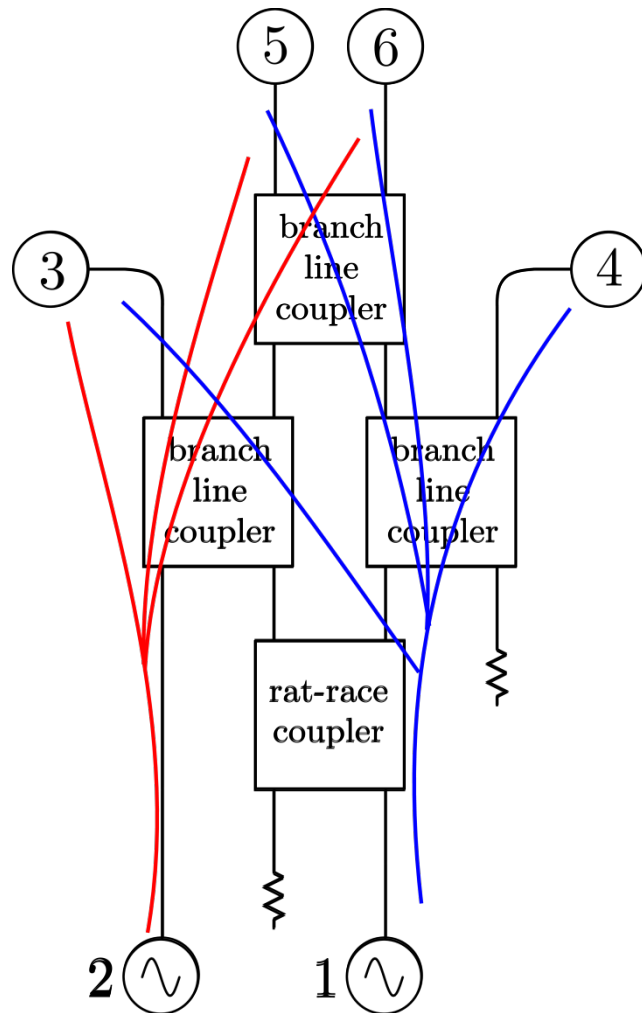
Six-Port Reflectometer

Operation principle



Six-Port Reflectometer

Operation principle



Port 1: $2a$

Port 2: $2b$

Port 3: $\frac{\sqrt{3}}{2}a - \frac{\sqrt{3}}{\sqrt{2}}b$

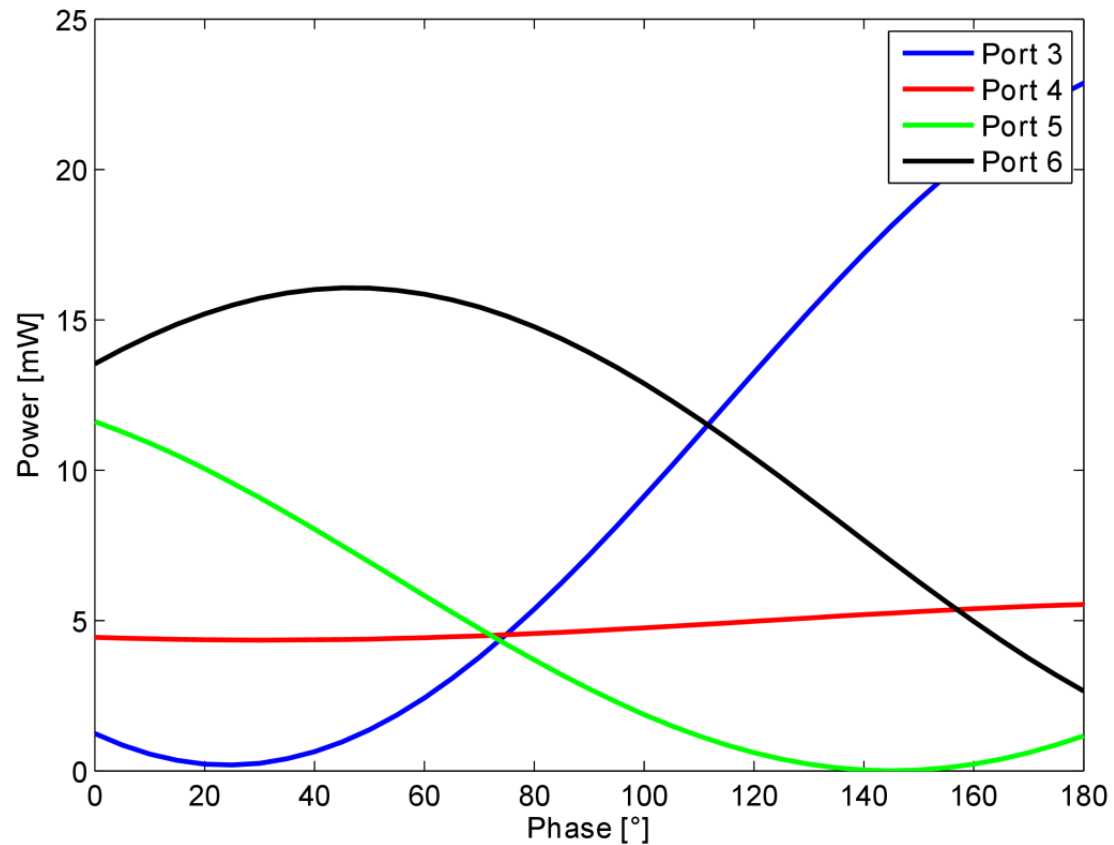
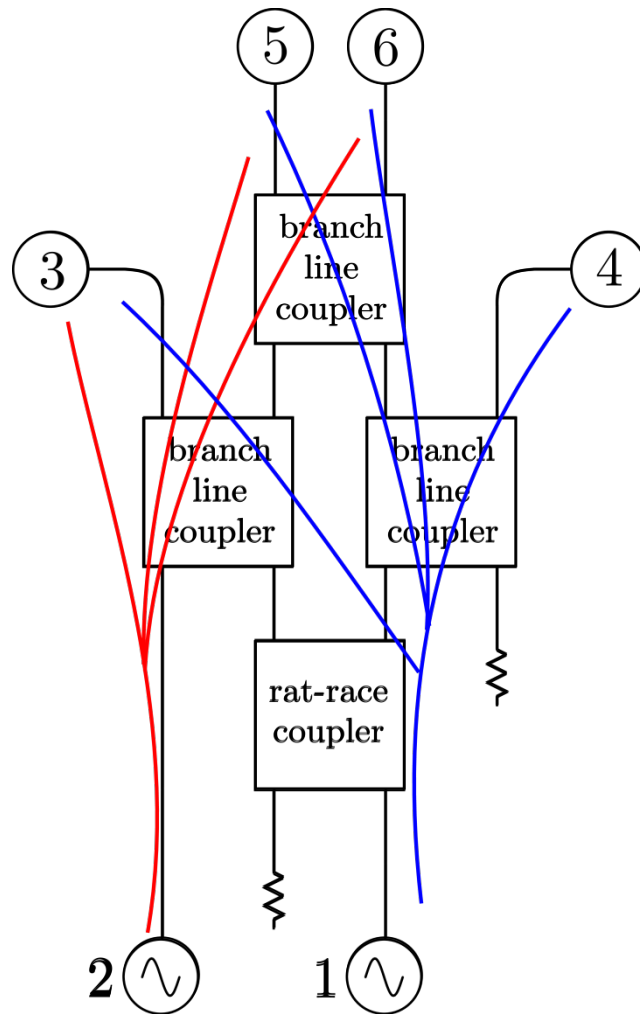
Port 4: $\frac{\sqrt{3}}{2}a$

Port 5: $\frac{\sqrt{3}}{2\sqrt{2}}a + j\frac{\sqrt{3}}{2}b - j\frac{\sqrt{3}}{2\sqrt{2}}a$

Port 6: $\frac{\sqrt{3}}{2\sqrt{2}}a - j\frac{\sqrt{3}}{2}a - j\frac{\sqrt{3}}{2}b$

Six-Port Reflectometer

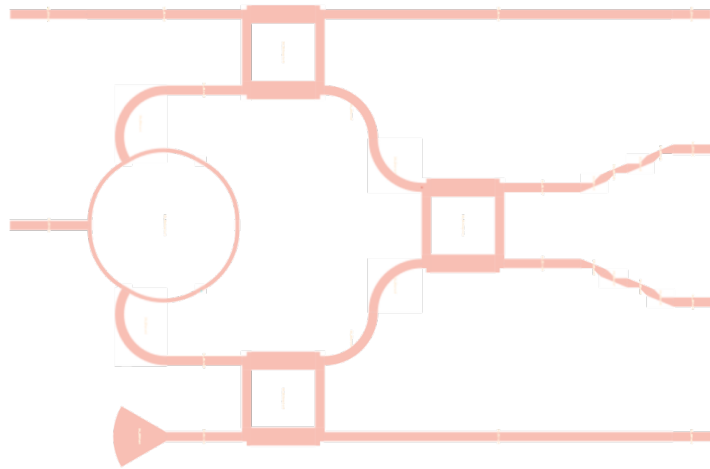
Operation principle



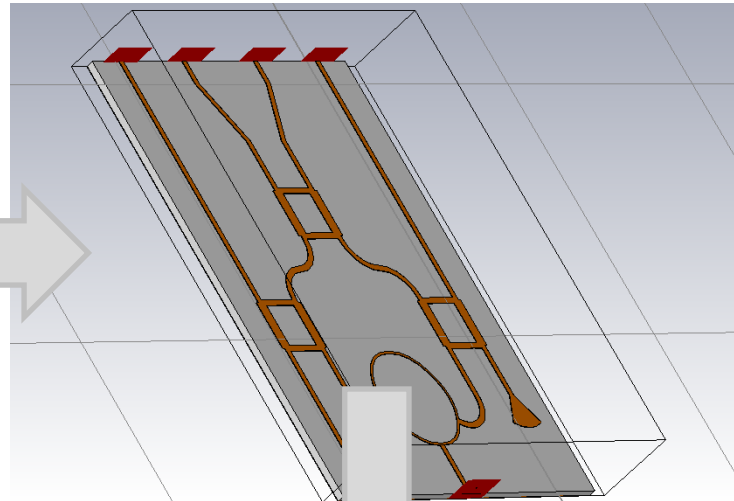
Six-Port Reflectometer Design



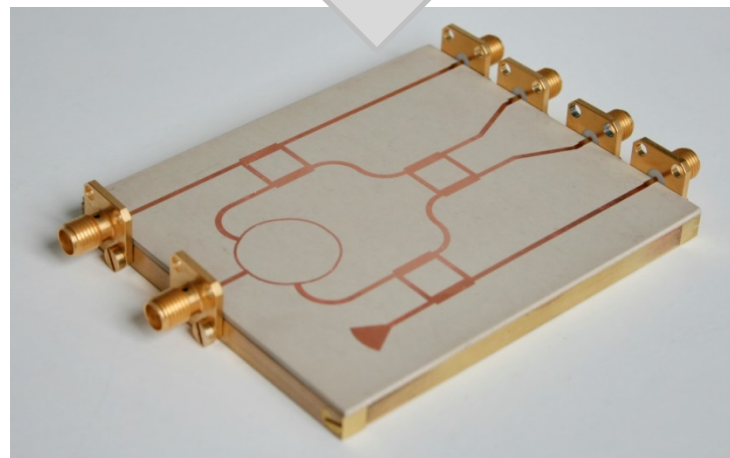
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Agilent ADS layout



*CST
simulation
model*



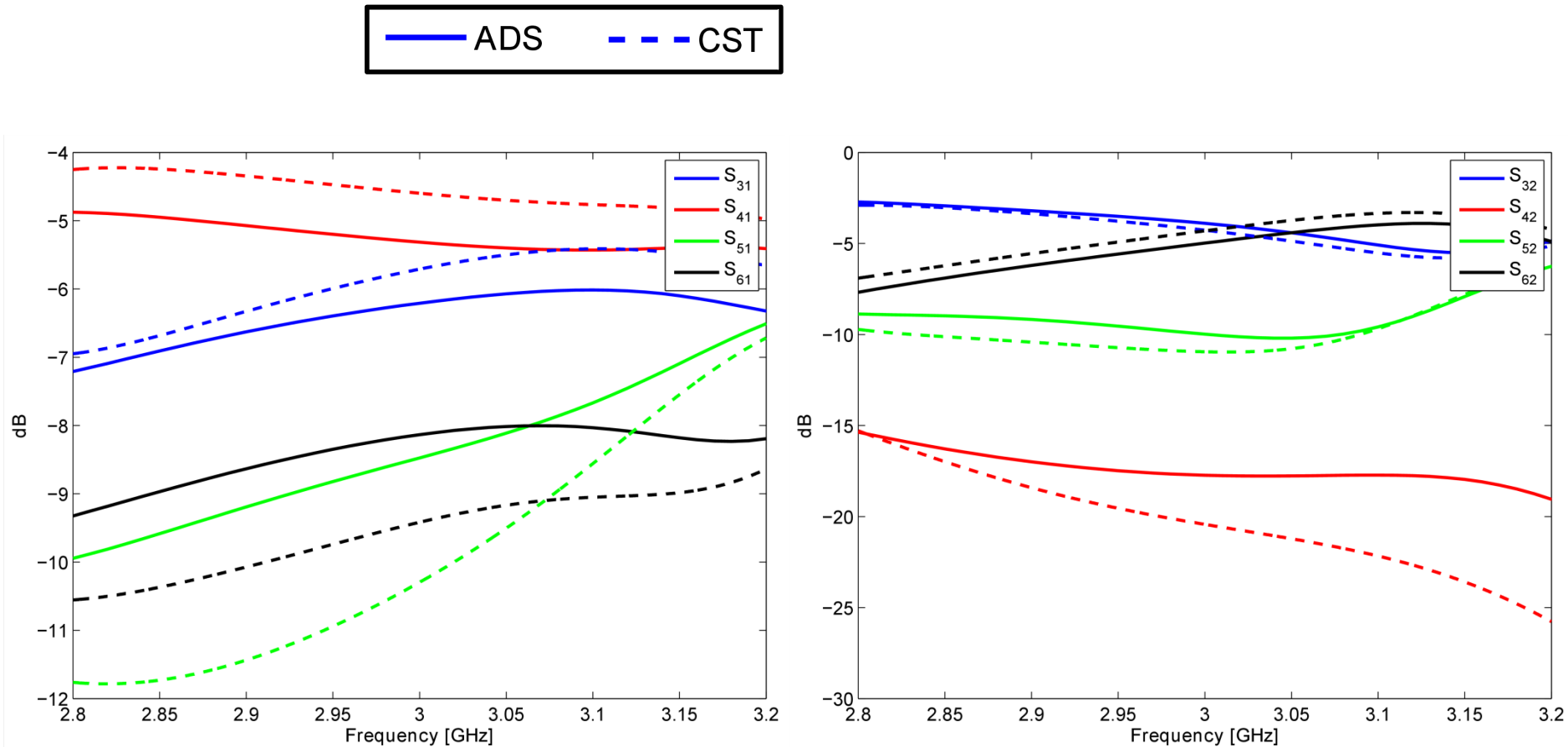
*Realized
circuit*

Rogers RT/Duroid® 6010LM

Dielectric constant	10.2
Substrate thickness	1.27 mm
Conductor thickness	18 μm

Six-Port Reflectometer Design

comparison between *ADS* and *CST* simulations



Six-Port Reflectometer Design

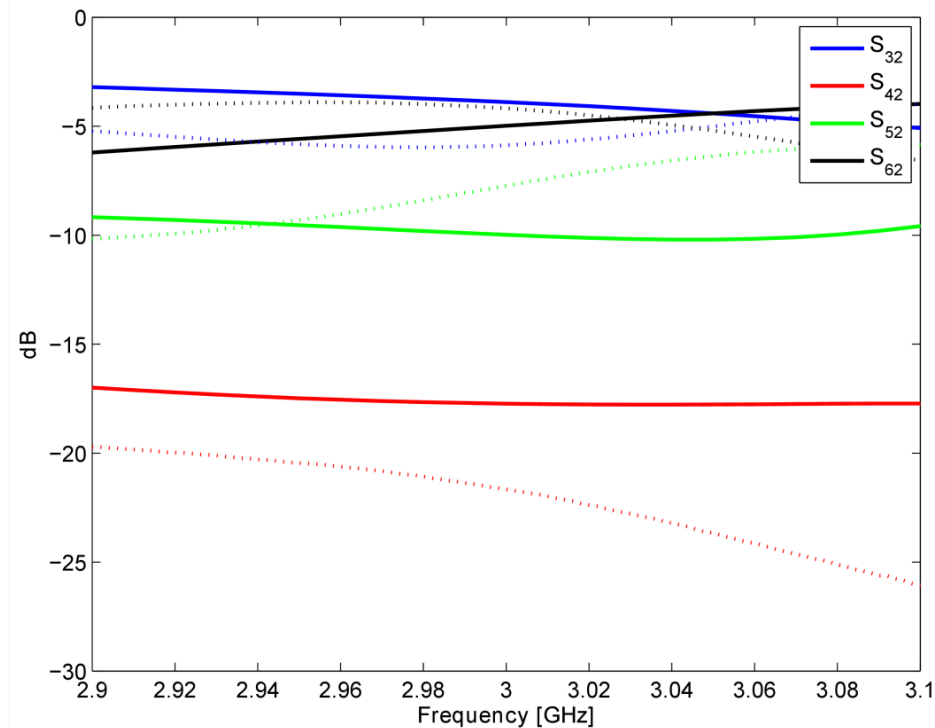
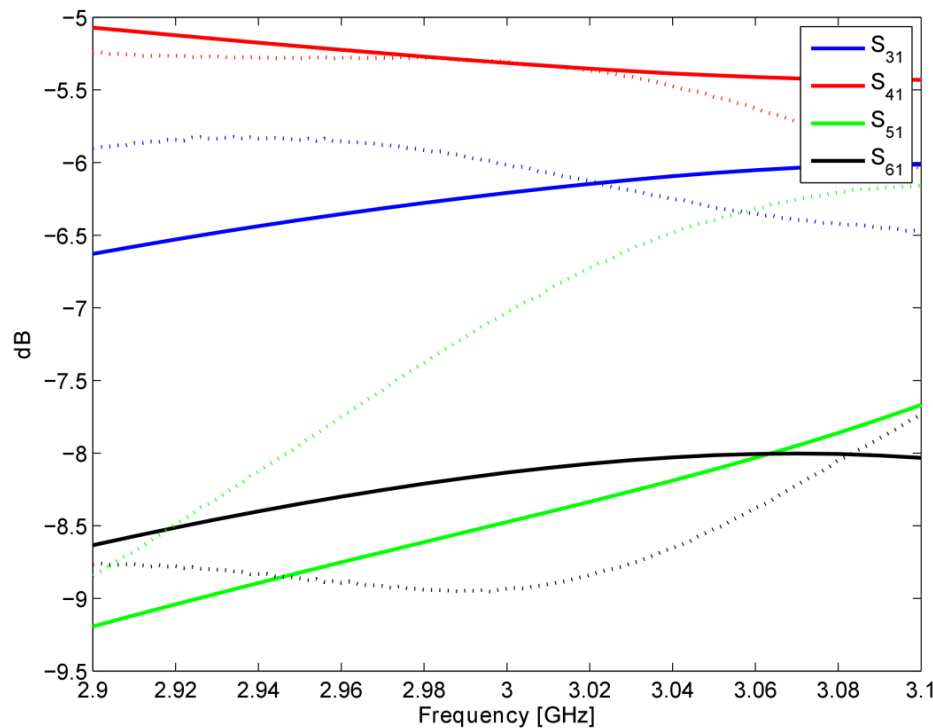
Comparison between *ADS* simulations and Measurements



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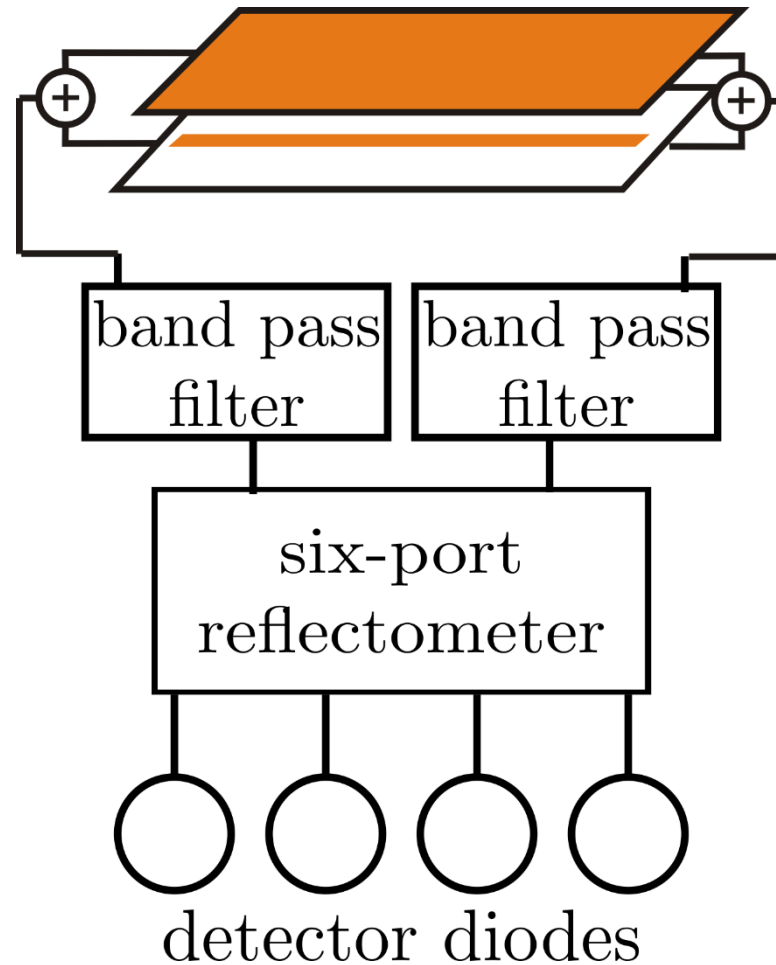
— ADS

····· Measurement



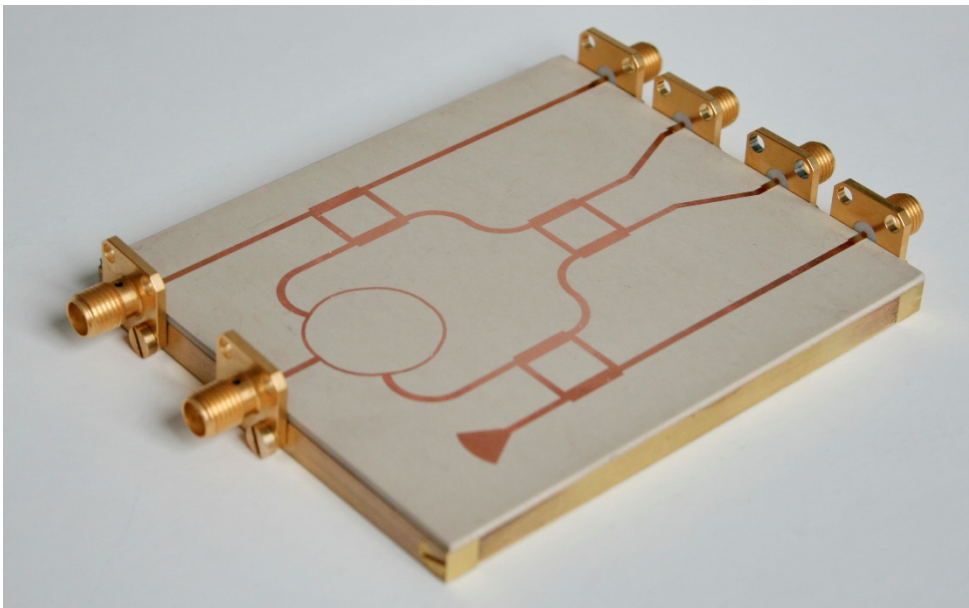
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Six-Port Reflectometer for Phase Difference Measurements



Measurement Setup

Six Port Reflectometer



Microstrip EBPM Pickup



Coupling loop (not to scale)

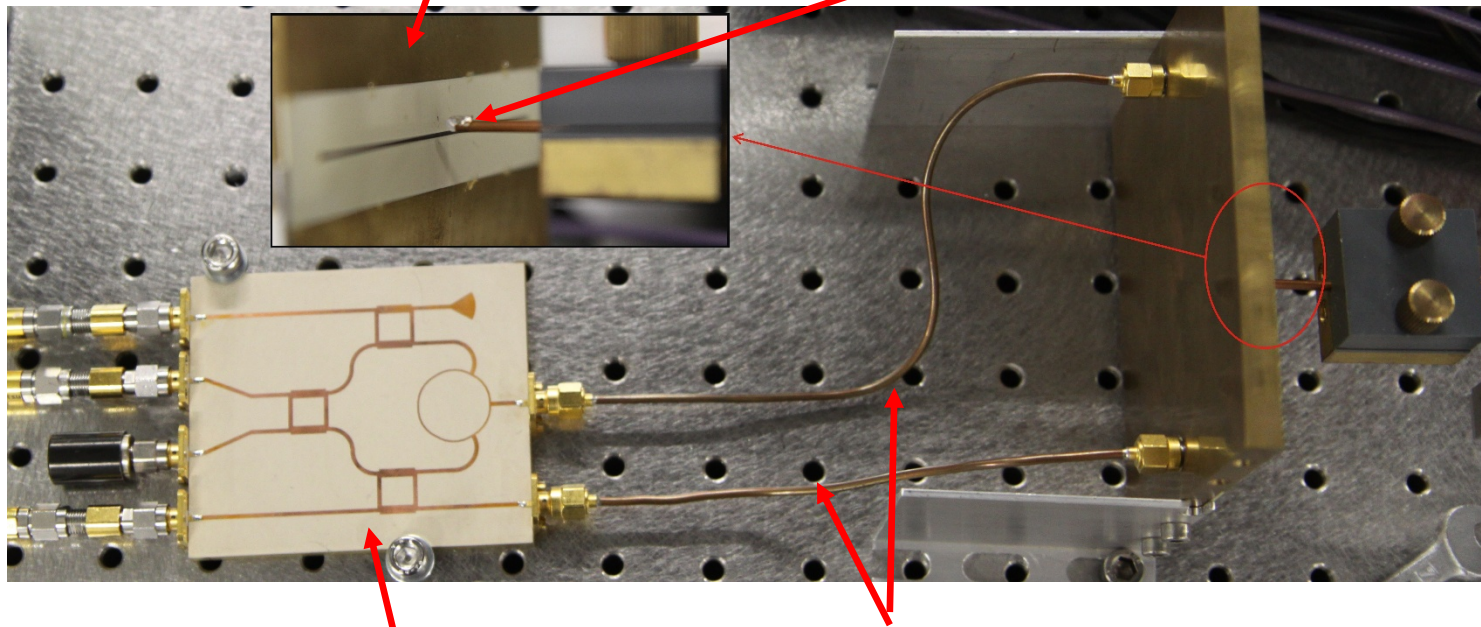


Measurement Setup

Beam induced excitation modeled with a small coupling loop in the vicinity of the transmission line

Non-hermetic TL Pickup

Coupling loop



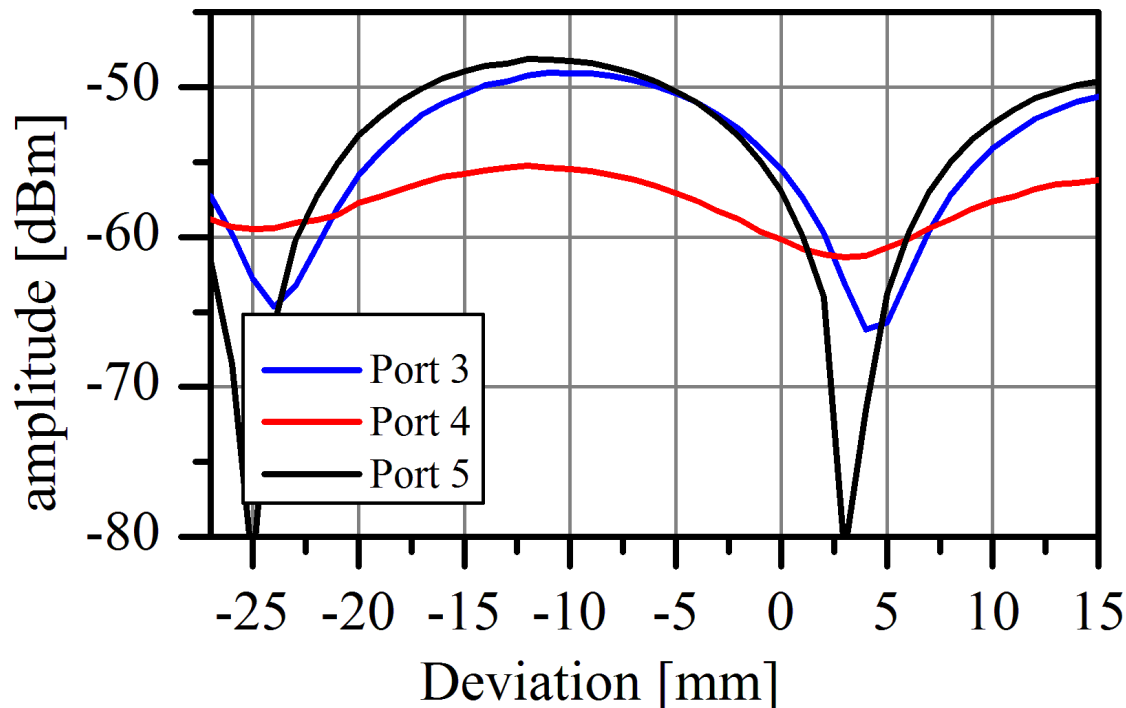
3D Micro-
Positioner
(not shown)

Six Port Reflectometer

Phase stable Semi-Rigid cables

Measurement Results

Detection range: 43 mm (1mm step size)



Power measurements

Port 4: 3 dBm variation due to

- mismatch &
- TL-losses

Port 3: 15 dBm periodic variation

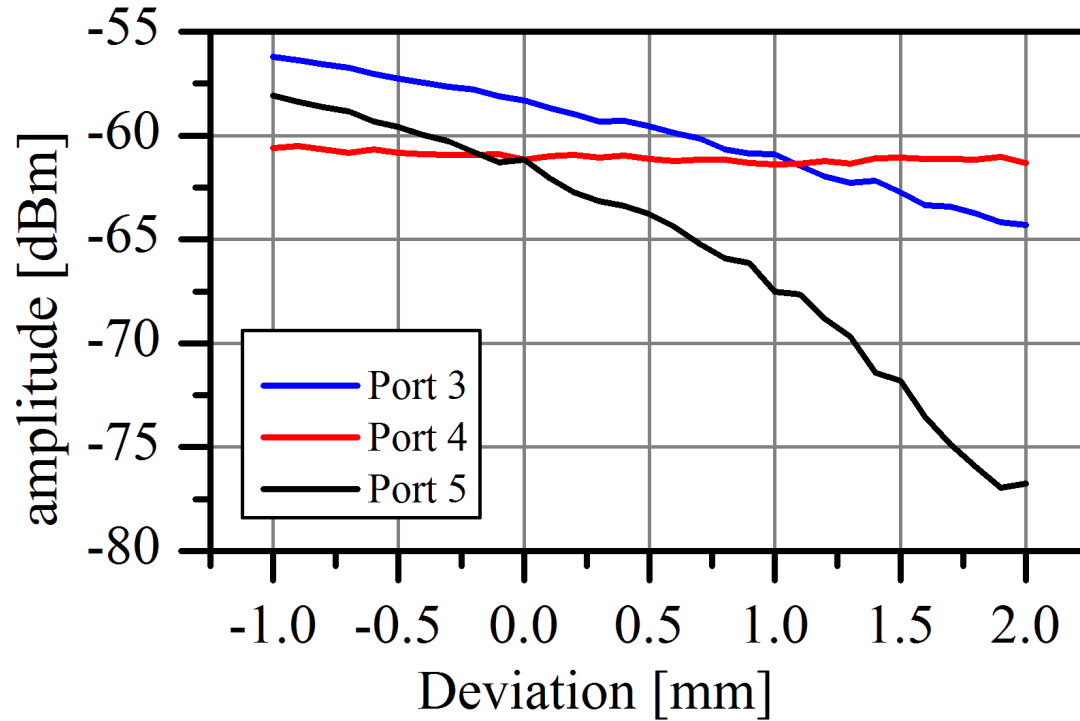
Port 5: 35 dBm periodic variation

phase ambiguity, leads to multiple solutions, when position is calculated

- Lower operation frequency needed for coarse detection

Measurement Results

Detection range: 3 mm (100 μ m stepsize)



Port #	Variation [dBm]	Sensitivity [dBm/ μ m]
4	1	0.0025
3	8	0.02
5	20	0.05

A standard power meter fulfills the requirements of 0.1dBm typically down to -70dBm.

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Conclusion

- A simple and passive read out scheme the EBPM Pickup structures for energy measurements of free-electron lasers such as FLASH or XFEL was introduced
- The EBPM requires a high dynamic range over the sensor length of 183 mm and high resolution of less than 20 μm
- The proposed design provides a sensitivity of more than 5dBm/mm beam offset for a mean value of -60dBm for the non hermetic test setup
- For the high resolution of less than 20 μm a sensitivity of 0.1dB at the given power level is sufficient

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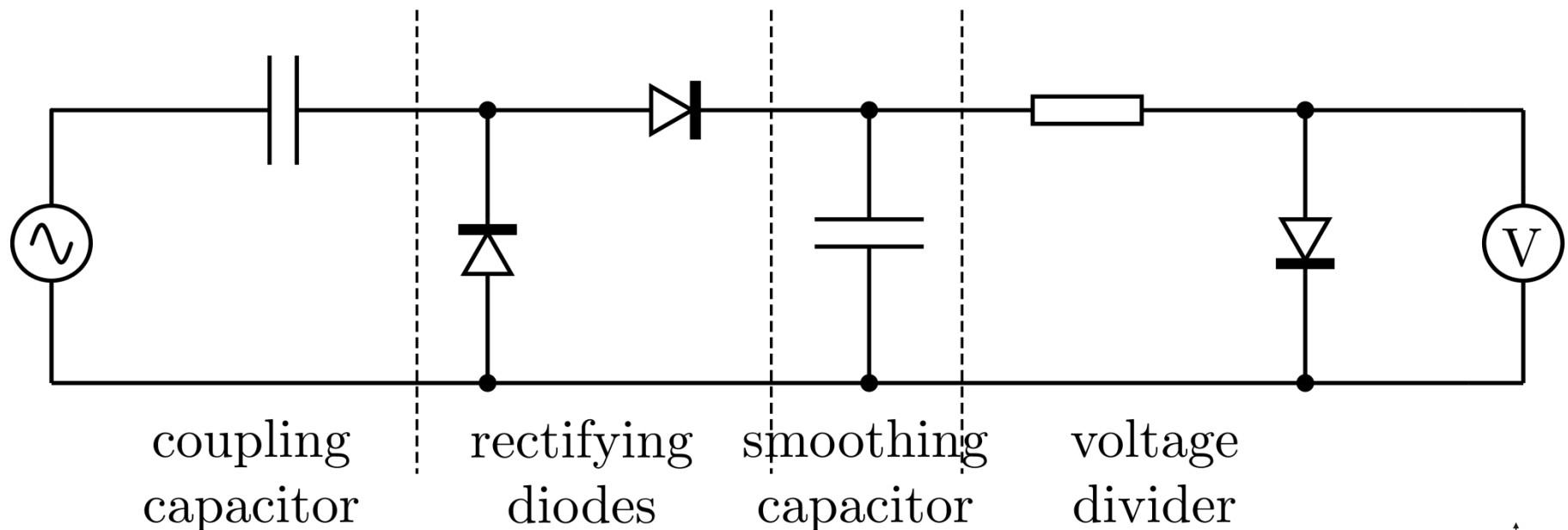
Outlook

- Realization of a Six-Port Spectrometer @ 1.3GHz to prevent phase ambiguity
- Further investigations about the detector circuit is needed

Outlook

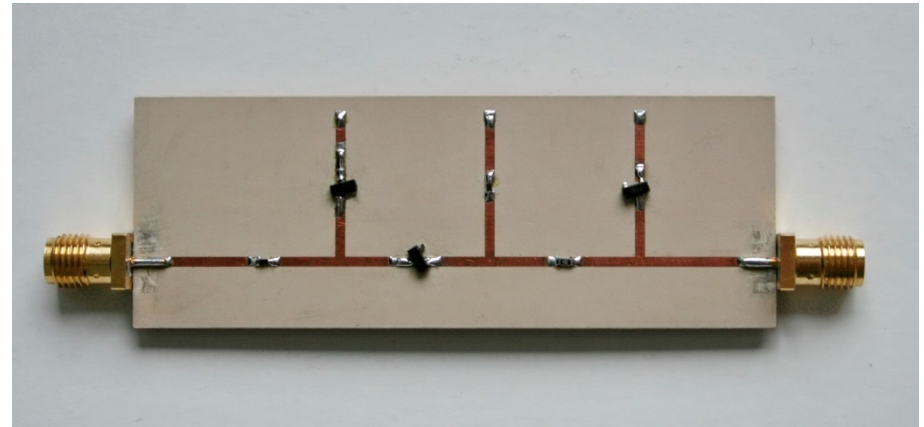
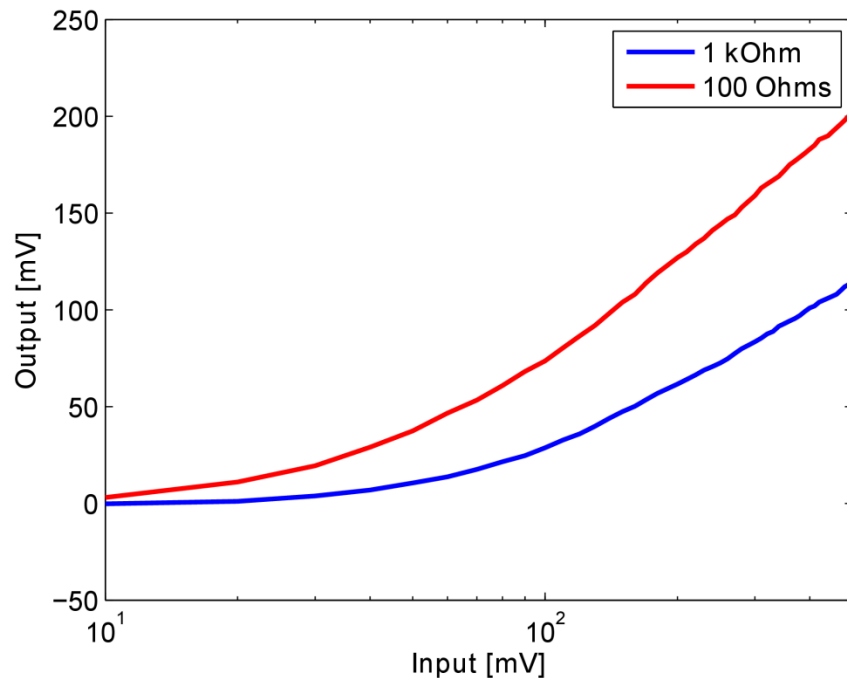
Diode Detector Circuit

- Power detection using Zero-Bias Schottky diodes
- dBm linear rectifier circuit based on a combination of a Villard circuit and a voltage divider



Outlook

Diode Detector Circuit



Detector circuit

- Sensitivity needs to be improved
- Adaption to input and output impedance necessary
- Integration to six-port discriminator



Thank you for your attention